

**Amendments to the Claims:**

This listing of claims will replace all prior listings of claims in the application.

**Listing Of Claims:**

**Claim 1 (currently amended):** A load-lock system comprising:  
a load-lock chamber arranged between a storage port which stores a substrate and a process chamber which processes the substrate in a process space maintained at a pressure lower than a pressure in the outside; and  
a dehumidifying unit which supplies dehumidified gas into said load-lock chamber  
~~chamber forms a dehumidified environment in said load-lock chamber.~~

**Claim 2 (original):** A system according to claim 1, wherein said dehumidifying unit has a controller which controls a humidity in said load-lock chamber so as to prevent moisture in said load-lock chamber from condensing when a temperature in said load-lock chamber drops.

**Claim 3 (original):** A system according to claim 1, wherein said dehumidifying unit has a pipe which communicates with said load-lock chamber, a cooler and a heater placed in the pipe, and a controller separately controls the cooler and heater.

**Claim 4 (original):** A system according to claim 3, wherein said dehumidifying unit has a filter for removing moisture, the filter being arranged between the cooler and the heater in the pipe.

**Claim 5 (currently amended):** A load-lock system ~~according to claim 1, further comprising:~~ another

a load-lock chamber arranged between a storage port which stores a substrate and a process chamber which processes the substrate in a process space maintained at a pressure lower than a pressure in the outside

a machine chamber arranged between said storage port and said load-lock chamber,

~~wherein said a dehumidifying unit which supplies dehumidified gas dehumidifies into said another machine chamber.~~

**Claim 6 (currently amended):** A system according to claim 5, wherein said dehumidifying unit has a controller which controls a humidity in said ~~another machine~~ chamber so as to prevent moisture in said load-lock chamber from condensing when a temperature in said load-lock chamber drops.

**Claim 7 (currently amended):** A system according to claim 6, wherein the controller calculates a humidity in said load-lock chamber and the humidity in said ~~another machine~~ chamber, and said dehumidifying unit controls the humidity in said ~~another machine~~ chamber so as to prevent moisture in gas flowing from said ~~another machine~~ chamber into said load-lock chamber from condensing when the temperature in said load-lock chamber drops, on the basis of a calculation result by the controller.

**Claim 8 (currently amended):** A system according to claim 5, wherein said dehumidifying unit has a pipe which communicates with said ~~another machine~~

chamber, a cooler and a heater placed in the pipe, and a controller separately controls the cooler and heater.

**Claim 9 (currently amended):** A system according to claim 5, further comprising a static eliminator which eliminates static electricity in said another machine chamber.

**Claim 10 (currently amended):** A system according to claim 5, wherein said another machine chamber includes a transport portion which transports the substrate between said storage port and said load-lock chamber.

**Claim 11 (currently amended):** An exposure processing system comprising:

a storage port which stores a substrate; an exposure processing unit which exposes the substrate in a process space maintained at a pressure lower than a pressure in the outside;

a load-lock chamber arranged between said storage port and said exposure processing unit; and

a dehumidifying unit which forms a dehumidified environment in supplies dehumidified gas into said load-lock chamber.

**Claim 12 (canceled).**

**Claim 13 (currently amended):** [[A]] An exposure processing system according to claim 11, further comprising:

a storage port which stores a substrate;  
an exposure processing unit which exposures the substrate in a process  
space maintained at a pressure lower than a pressure in the outside;  
a load-lock chamber arranged between said storage port and said exposure  
processing unit;  
a mini-environment arranged between said storage port and said load-lock  
chamber,  
~~wherein~~ said a dehumidifying unit which supplies dehumidified gas into  
said mini-environment.

**Claim 14 (original):** A device manufacturing method comprising:

an exposure step of exposing a substrate using an exposure processing  
system as defined in claim 11; and  
a development step of developing the exposed substrate.

**Claim 15 (new):** A device manufacturing method comprising:  
an exposure step of exposing a substrate using an exposure processing  
system as defined in claim 13; and

a development step of developing the exposed substrate.